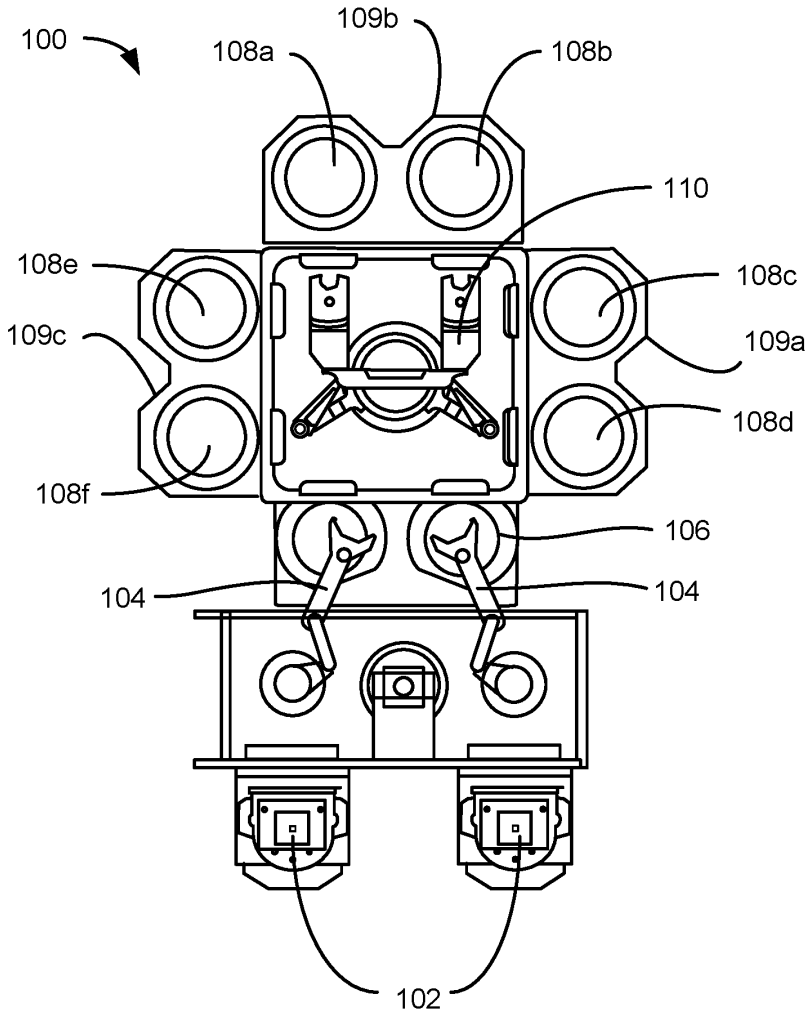

100
109b
108a
108b
110
108e
108c
109c
109a
108d
108f
106
104
104
102

FIG. 1

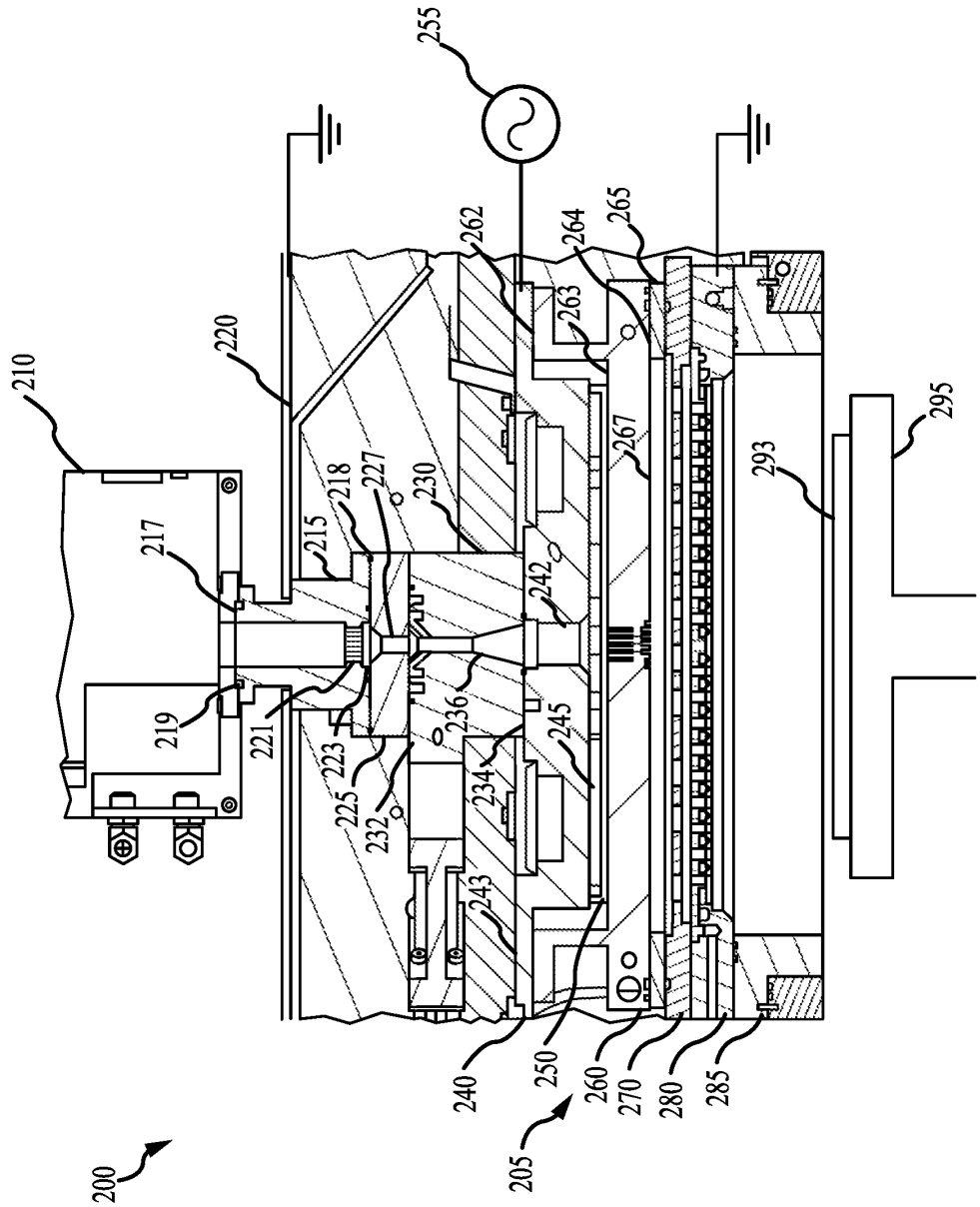

255
262
264
265
263
220
210
267
295
293
218
227
230
217
215
242
219
221
223
236
245
225
232
234
243
240
250
260
270
280
285
205
200

FIG. 2

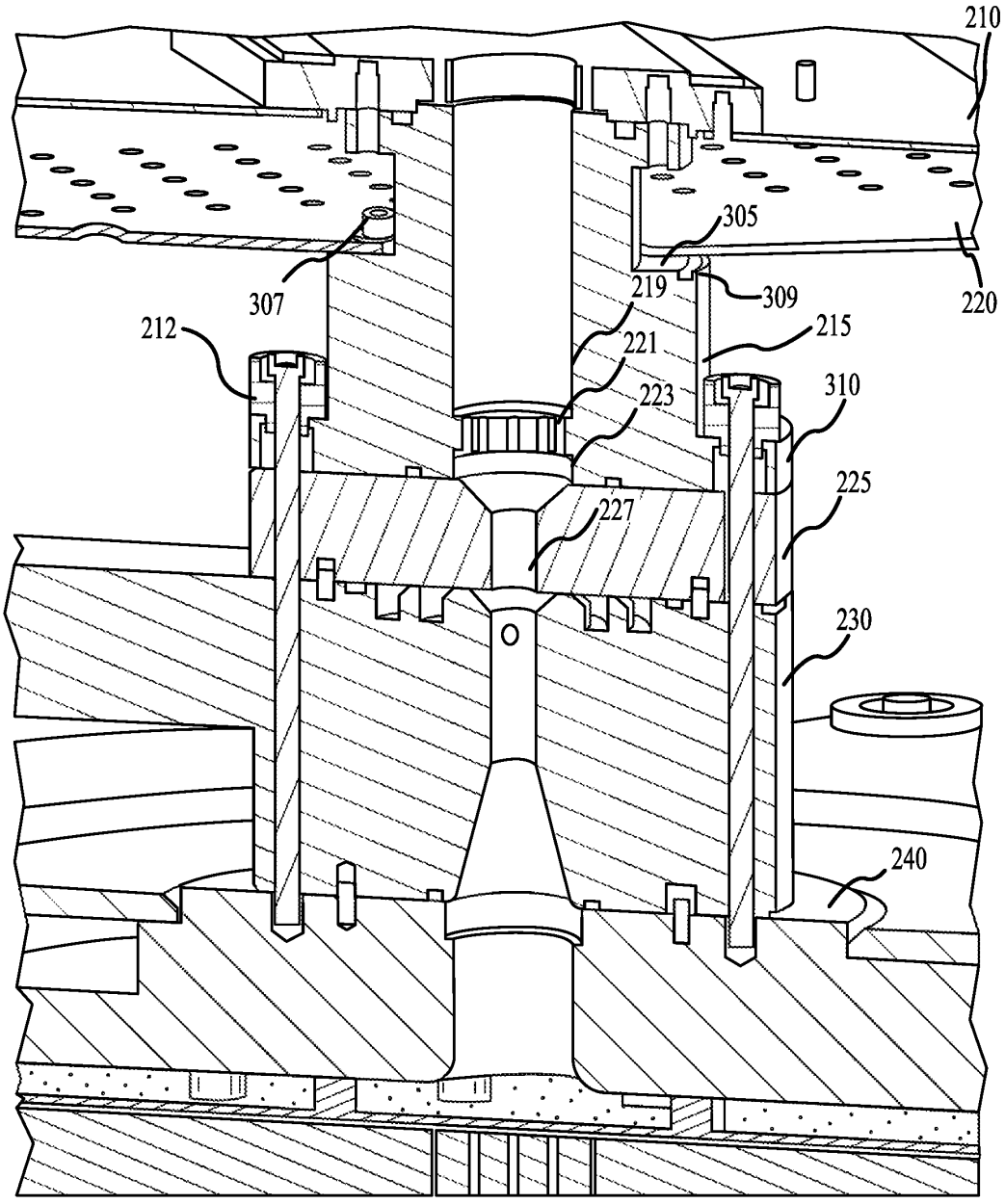


FIG. 3

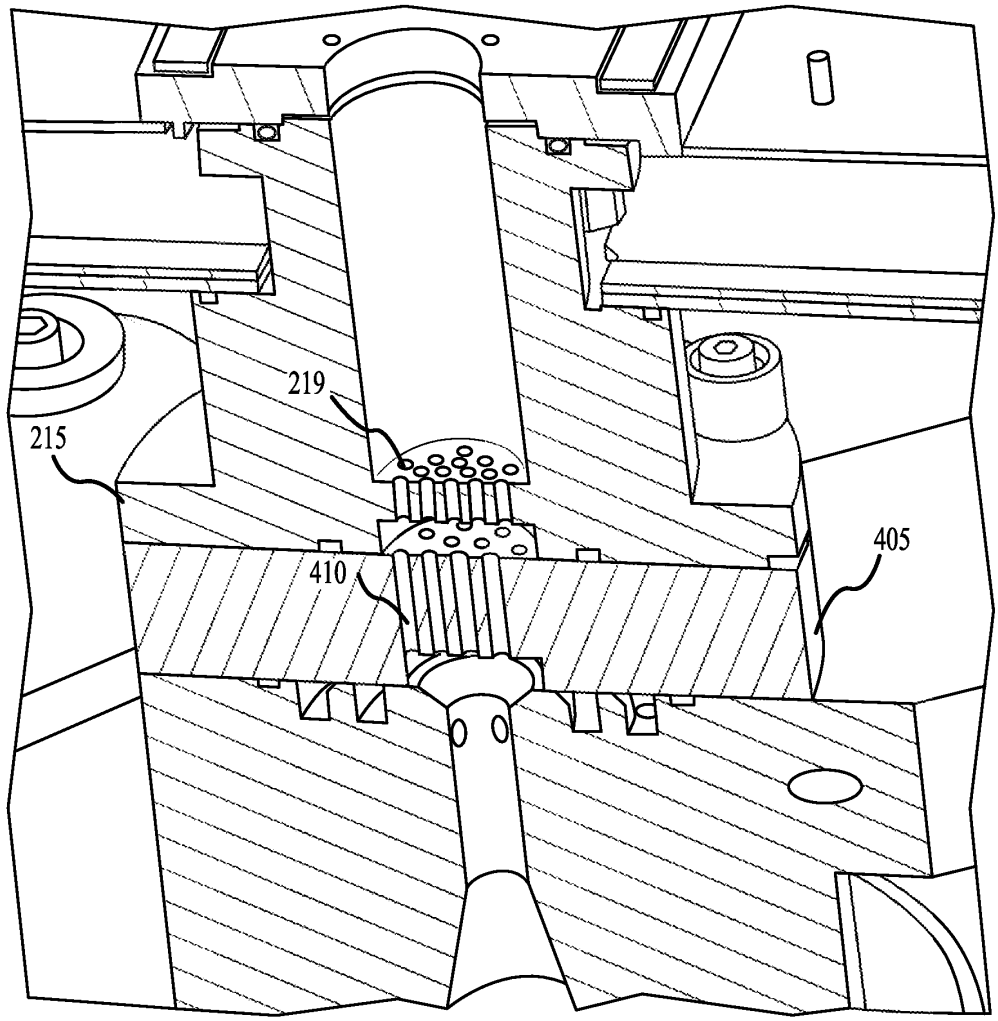


FIG. 4

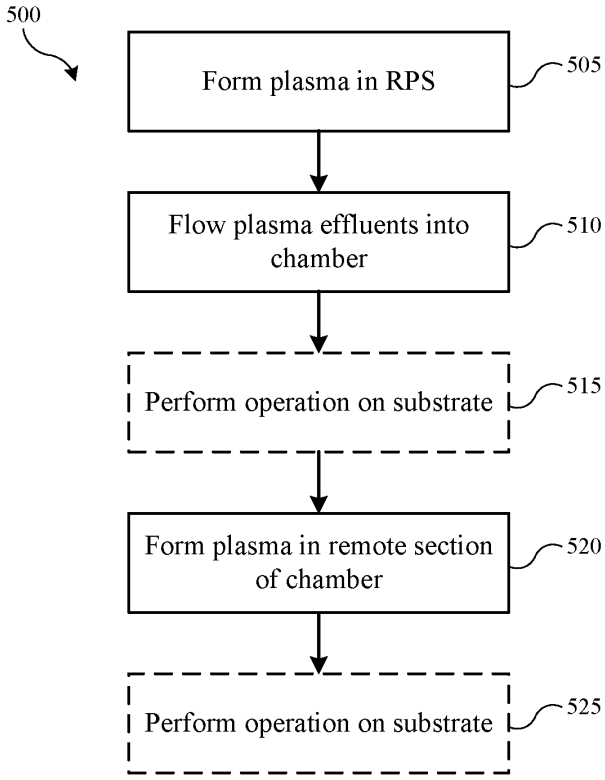

500
Form plasma in RPS
505
Flow plasma effluents into chamber
510
Perform operation on substrate
515
Form plasma in remote section of chamber
520
Perform operation on substrate
525

FIG. 5